



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535  
First Named Inventor : Takuya SUGAWARA, et al.  
Filed : June 28, 2004  
TC/A.U. : 2812  
Examiner : To Be Assigned  
Docket No. : 010986.55104US  
Customer No. : 23911

Title : Substrate Treating Method and Production Method  
for Semiconductor Device

**REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT**

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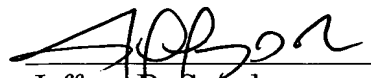
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Respectfully submitted,

May 20, 2005

  
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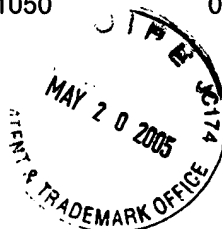
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10/500,214	03/17/2005	2812	1050	010986.55104US	9	9	1

23911

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CONFIRMATION NO. 2535

## FILING RECEIPT



\*OC000000015722867\*

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## Applicant(s)

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## Assignment For Published Patent Application

Tokyo Electron Limited, Minato-ku, Tokyo, JAPAN  
*kw*

Power of Attorney: The patent practitioners associated with Customer Number 23911.

## Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP02/13550 12/25/2002

## Foreign Applications

JAPAN 2001-394546 12/26/2001

Projected Publication Date: 07/21/2005

Non-Publication Request: No

Early Publication Request: No

**Title**

Substrate treating method and production method for semiconductor device

**Preliminary Class**

438

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